micromachines

an Open Access Journal by MDPI

IMPACT FACTOR 3.0

Indexed in: PubMed

CITESCORE 6.0

Recent Advances in Metal Oxide Thin Films and Nanostructures for Diverse Applications

Guest Editor:

Dr. Phuoc Huu Le
1. Center for Plasma and Thin Film Technologies, Ming Chi University of Technology, New Taipei City 24301, Taiwan
2. Department of Physics and Biophysics, Can Tho University of Medicine and Pharmacy, Can Tho 94000, Vietnam

Deadline for manuscript submissions:
closed (30 November 2024)

mdpi.com/si/192035

Message from the Guest Editor

Dear Colleagues,

We would like to invite you to submit your work to this Special Issue, focused on “Recent Advances in Metal Oxide Thin Films and Nanostructures for Diverse Applications”. This Special Issue aims to provide a snapshot of the state of the art in the preparations, characterizations, and applications of MO thin films and nanostructures.

In particular, the topics of interest include, but are not limited to, the following:

- MO thin film growths and characterization techniques;
- Synthesis of MO nanostructures, properties, and applications;
- Nanomechanical properties of MO thin films and nanostructures studied by the nanoindentation technique;
- Photocatalytic degradation of pollutants and photoelectrochemical activity of MO thin films and nanostructures;
- Functional properties and applications of MO thin films and nanostructures (e.g., HER, fuel cells, solar cells, hard coatings, antimicrobial activity, anti-bacteria, photodetectors, sensing, electronic devices, optoelectronics, memories, etc.);
- Theory, modeling, atomistic simulation, and numerical analysis of MO thin films and nanostructures.

Dr. Phuoc Huu Le
Guest Editor

Special Issue

Indexed in:
PubMed

CITESCORE
6.0

IMPACT
FACTOR
3.0

an Open Access
Journal by MDPI

Editor-in-Chief

Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

Author Benefits

Open Access: free for readers, with article processing charges (APC) paid by authors or their institutions.
High Visibility: indexed within Scopus, SCIE (Web of Science), PubMed, PMC, Ei Compendex, dblp, and other databases.
Journal Rank: JCR - Q2 (Instruments and Instrumentation) / CiteScore - Q1 (Mechanical Engineering)

Contact Us

Micromachines Editorial Office
MDPI, Grosspeteranlage 5
4052 Basel, Switzerland

Tel: +41 61 683 77 34
www.mdpi.com

mdpi.com/journal/micromachines
micromachines@mdpi.com
𝕏@micromach_mdpi